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Docket No.: T2171.0214  
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Tomoyasu Aoshima

Application No.: 10/773,244

Confirmation No.: 7164

Filed: February 9, 2004

Art Unit: 1763

For: ANISOTROPIC WET ETCHING OF  
SILICON

Examiner: Not Yet Assigned

STATUS INQUIRY

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Please advise us of when we might expect to receive an Office Action from the Patent and Trademark Office.

Dated: April 12, 2005

Respectfully submitted,

By *Michael J. Scheer*  
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